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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applic. No. : 09/873,230 Confirmation No: 4487
Applicant : Norbert Benesch, Claus Schneider, Lothar Pfitzner
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Technology Center 2600

INFORMATION DISCLOSURE STATEMENT

Hon. Commissioner for Patents

Sir:

In accordance with 37 C.F.R. 1.98 copies of the following patents and/or publications are submitted herewith:

M. G. Moharam et al.: "Three-dimensional vector coupled-wave analysis of planar-grating diffraction", *J. Opt. Soc. Am.*, Vol. 73, No. 9, September 1983, pp. 1105-1112;

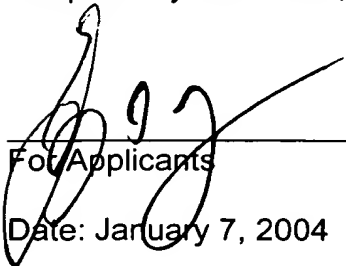
M. G. Moharam et al.: "Rigorous coupled-wave analysis of metallic surface-relief gratings", *J. Opt. Soc. Am. A*, Vol. 3, No. 11, November 1986, pp. 1780-1787;

S. S. H. Naqvi et al.: "Etch depth estimation of large-period silicon gratings with multivariate calibration of rigorously simulated diffraction profiles", *J. Opt. Soc. Am. A*, Vol. 11, No. 9, September 1994, pp. 2485-2493;

Christopher J. Raymond et al.: "Multiparameter grating metrology using optical scatterometry", *J. Vac. Sci. Technol. B*, Vol. 15, No. 2, March/April 1997, pp. 361-368;

Jörg Bischoff et al.: "New aspects of optical scatterometry applied to microtechnology", *SPIE*, Vol. 3215, 1997, pp. 144-155.

Respectfully submitted,



For Applicants

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